

3/A
11-13-78
AB

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of: Wilk *et al.*
Provisional Serial No.: 60/063,010
Serial No.: TBD
Provisional Filed: 10/23/97
Filed: Herewith
For: Low Temperature Method for Forming a Thin, Uniform Oxide

Docket: TI-24742
Examiner: TBD
Art Unit: TBD

PRELIMINARY AMENDMENT

September 28, 1998

Ass't Commissioner for Patents
Washington, DC 20231

MAILING CERTIFICATE UNDER 37 CFR § 1.8
I hereby certify that this correspondence is being deposited with the
United States Postal Service as first class mail in an envelope
addressed to: Assistant Commissioner for Patents, Washington,
DC 20231 on
October 26, 1998.
Sue Short
Sue Short

Examiner:

Prior to examination and calculation of fees, please amend the above-identified application
as follows:

IN THE SPECIFICATION:

On Page 1, lines 5-9, delete the table in its entirety and replace with the following:

<u>Filing</u> <u>Date</u>	<u>Appl. No.</u>	<u>Title</u>
7/31/97	08/904,009	Method For Thin Film Deposition On Single-Crystal Semiconductor Substrates
10/23/97	60/063,010	Low Temperature Method for Forming a Thin, Uniform Oxide

On Page 1, lines 14-19, delete the table in its entirety and replace with the following:

<u>Filing</u> <u>Date</u>	<u>Appl. No.</u>	<u>Title</u>
7/31/97	08/904,009	Method For Thin Film Deposition On Single-Crystal Semiconductor Substrates